



PATENT  
Attorney Docket No.: SSI-00501

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Maximilian A. Biberger et al.

Serial No.: 09/912,844

Filed: July 24, 2001

For: **HIGH PRESSURE PROCESSING  
CHAMBER FOR  
SEMICONDUCTOR SUBSTRATE**

) Group Art Unit: 1763

) Examiner: Ram N. Kackar

) **AMENDMENT AND RESPONSE TO  
FINAL OFFICE ACTION MAILED ON  
March 13, 2003**

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Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

Sir:

This Amendment and Response is submitted in response to the final Office Action mailed on March 13, 2003. This Amendment and Response uses the revised amendment format stated in "Amendments in a Revised Format now Permitted," signed January 31, 2003, and published in the United States Patent and Trademark Office Official Gazette Notice of February 25, 2003.

CERTIFICATE OF MAILING (37 CFR § 1.8(a))

I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the U.S. Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to the: Assistant Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450

HAVERSTOCK & OWENS LLP.

Date: 5-12-03

By: Juanita Carolina